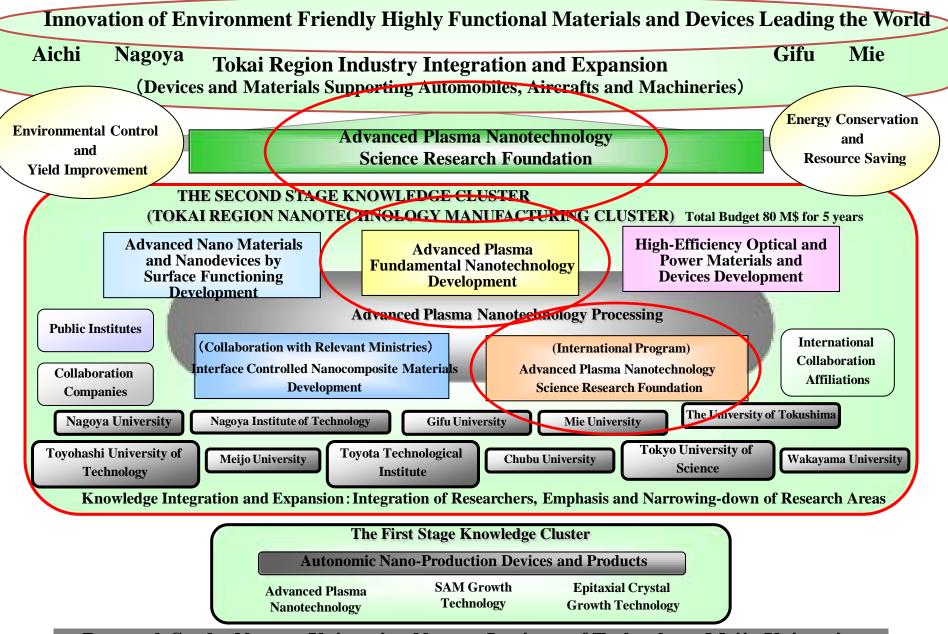
Plasma Science Global Innovation Bases

Masaru Hori

Department of Electric Engineering and Computer Science Plasma Nanotechnology Research Center (PLANT) Nagoya University, Japan

GOAL OF THE SECOND STAGE KNOWLEDGE CLUSTER



Research Seeds: Nagoya University, Nagoya Institute of Technology, Meijo University



Material • Device

Innovation

SELU

Environment

Innovation



Global Innovations

Plasma Sciences

プラズマ(-)

プラズマ(+)



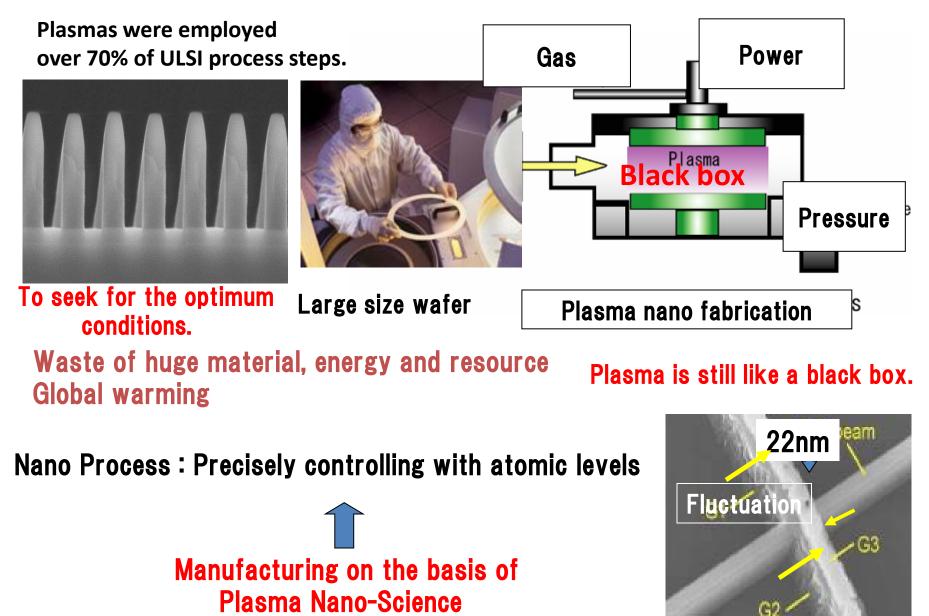
Well being Innovation



Medicine Innovation

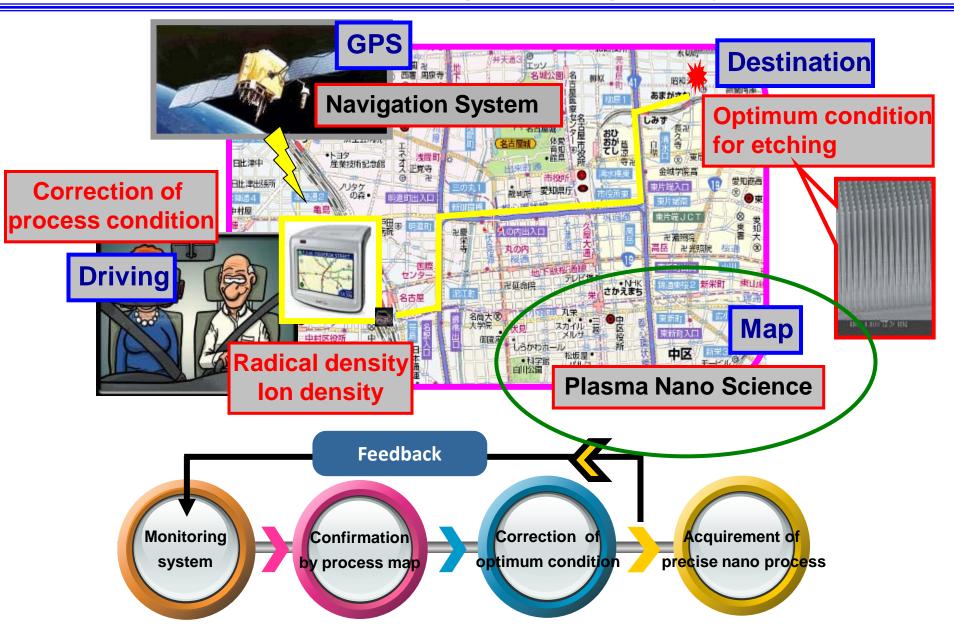


Manufacturing by Try and Error

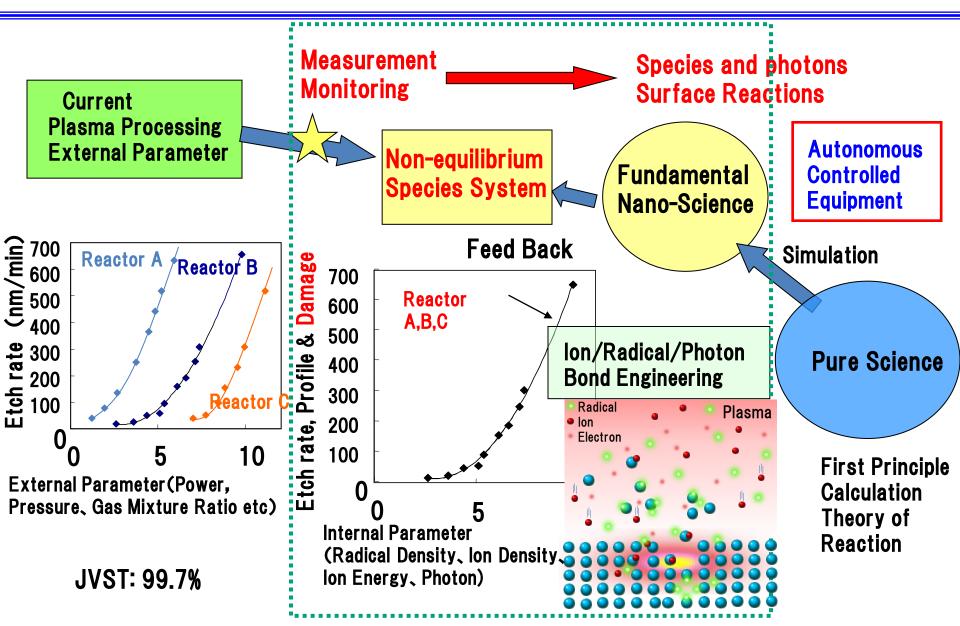


Autonomic Nano-Production Device

for Plasma Processing with navigation system



Conclusion: Foundation of Plasma Nano Science *In-situ* analysis Species vs Surface Reactions



Perspective of Plasma Science Global Innovations

Innovation of System, Process and Material Attributed to Own Idea Synergy by International Team Lab

Manufacturing Science World Wide

Vigorous and Dynamic Plasma Community Transfer Intelligence to Industries Integration of Academy Cultivation of Human Resources

Nagoya University Plasma Nanotechnology Center (PLANT) since 2006

17 Profs and advanced plasma equipment over 90 are working

2 patents (93 Registered) 4th Floor (350m²)



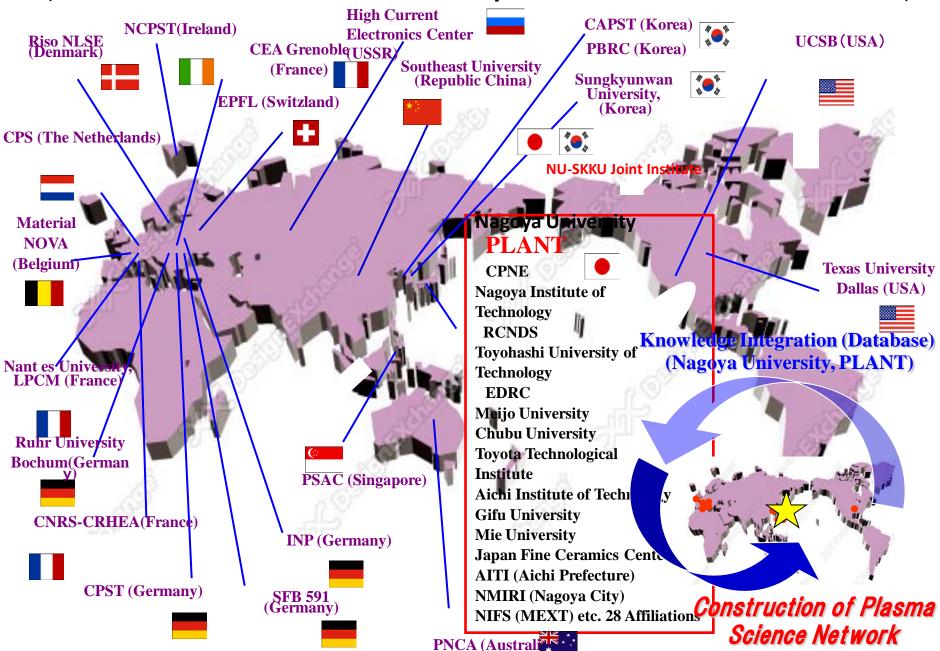


Plasma Center for Industrial Applications (PLACIA)



Unique Technical Transferring System From Science to Global Business Company : 303, Member 667

Advanced Plasma Nanotechnology Science Cluster Research Bases (Collaboration with 28 affiliations in Japan and 23 Affiliations in the world)



Road Map: Plasma Process Technology

	2010	2020	2030	2040
Dut	Device dimension 35nm	25nm	10nm 5nm	2.5nm 1nm
	Compound Semiconductor Nano-scale Logic Device Molecular Device Atomic Device			
	High Definition Flexible E	Display 3-Dimension Display livery system Bio-Mechanics-fusio		Projection in Brain
	Ultra Efficient Solar (ectric/Thermoelectric convers	
Output Products, Application	Environmen	tal Detox Hi-Efficient Agricult	ural/Marine production Nar	o Detox Global Restoration
	Hi-Efficient Manufac. Too	ol 1 Atom-Accurate Ma	nufac. Tool Organic/Bi	o Self Assemble Manufac. Tool
Development Manufacturing technology	Engineering makes Se	eds(Principle) to Product	ion Technology	
	Hi Precisio	on / Hi Productivity / Large A	rea / Stable Production Tec	chnology
nol D	Developmen	t for Feedback Control Tecl	anology using Monitor and	Simulation
le / le		ning -> Pin-Point Control -> Pin-Po		
Ma	Monitor- ,Simulator - Fri	- / /		
	,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,			
	Top-down Process			
e e	Principle of Species Gener	ation Control Nano, µ - m sca	ale, Lo - Hi Pressure, Gas/Li	quid/Solid(Surface), Phase mix
	Principle of Surface Reaction	on 1 Atom/Molecule Contro	Control of Functional Un	it Organic/Bio Material
		Vertical/Lateral Atomically-co		ecular Manipulation
	Bottom-Up Process	/		
	Principle of Selective Reac	tion/Self-Assemble Clarify	& Realize of No-defect / Ultra	Hi-Speed reaction
		Ultimate Controlled Beam	Process for Defect Self-	
l e		Perfect No-Defect Hi-Spee	d Self- Synergic Re	action in Large area
	Common Basic Technolog	Assembled films / Materia	s	
	Diagnostics Ultimate precise N	lo Disturb. 3D Flash Diag. Nano s	truct./Elec.Charact.Diag. Progno	stic Diag.
	Simulation Ultimate corre	ect Multi Scaled Time/	Space Flash (intuitive) Algo	rithm
	DATABAS	E : Atom, Molecule Re	action / Surface Read	ction / Mechanism

Plasma Electronics Division, JSAP

Innovation

Rapid Impact in Japan: Aging Population Combined with the Diminishing Number of Children

Concept of Plant and Building for Plasma Research and Its Applications to Industries in University to make global innovations

What system is ideal?

For the Sake of Sustainable Progress of Humankind



On the basis of Plasma Science & Technology